IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of	)	
Shunpei YAMAZAKI et al.	)	ATTN: New Applications
Based On: JP 2002-294305	)	
Filed: October 7, 2002	)	
For: METHOD OF IRRADIATING	)	
LASER, LASER IRRADIATION	)	
SYSTEM, AND	)	
MANUFACTURING METHOD	)	
OF SEMICONDUCTOR DEVICE	)	

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Specification is reflected on page 2 of this paper.

Remarks begin on page 3 of this paper